

FIG. 1

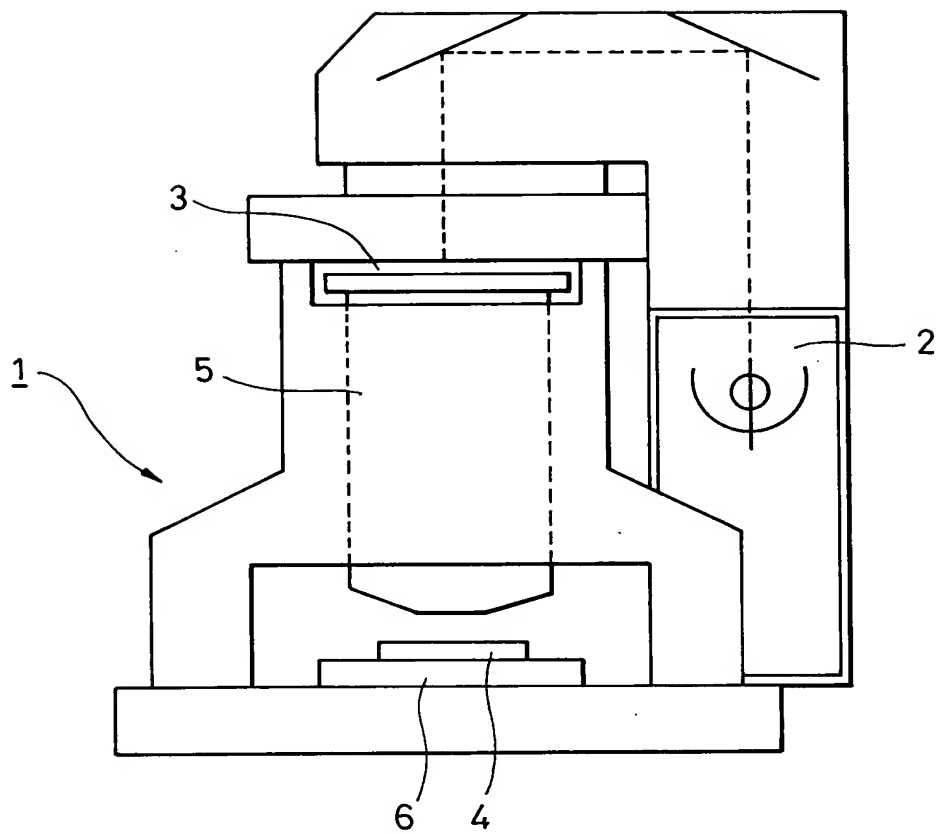
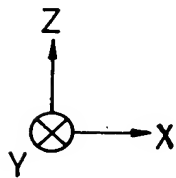
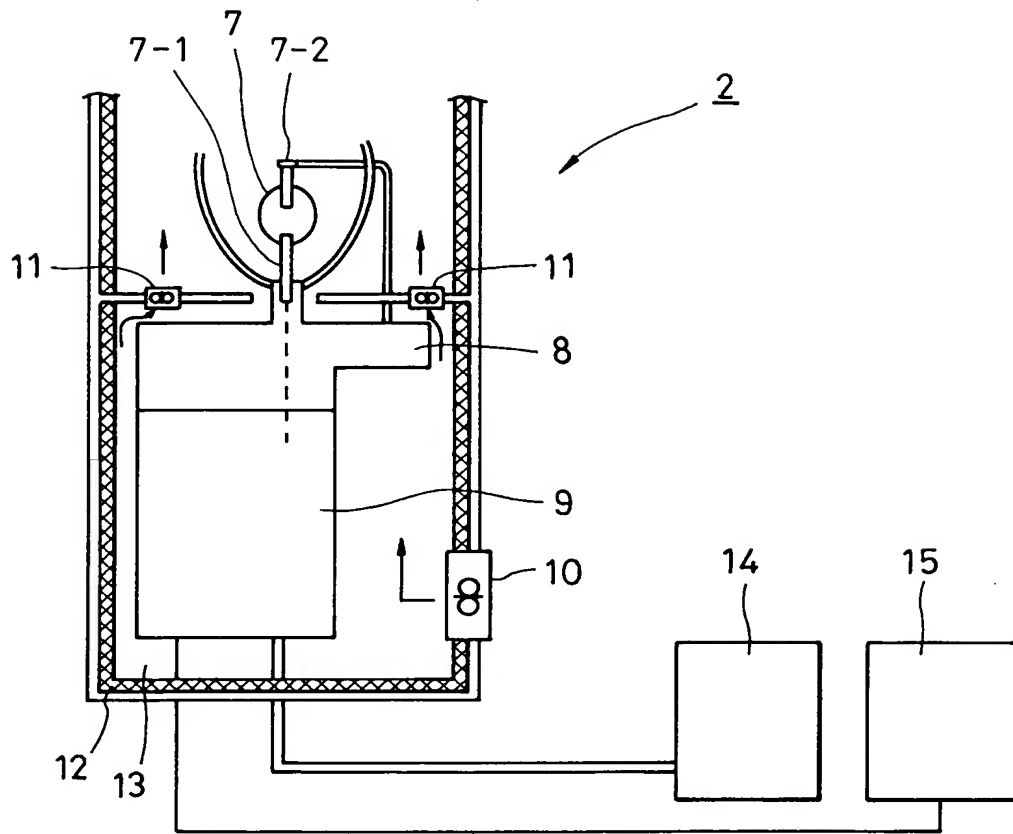


FIG. 2



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FIG. 3

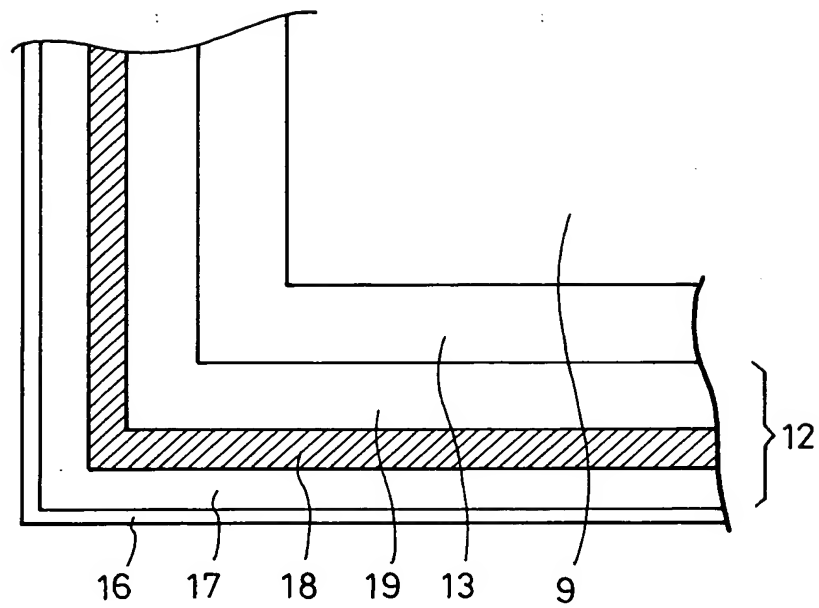


FIG. 4

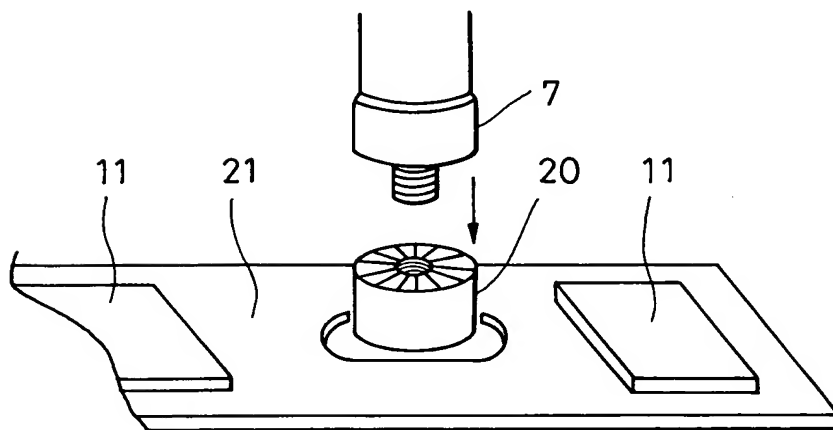


FIG. 5

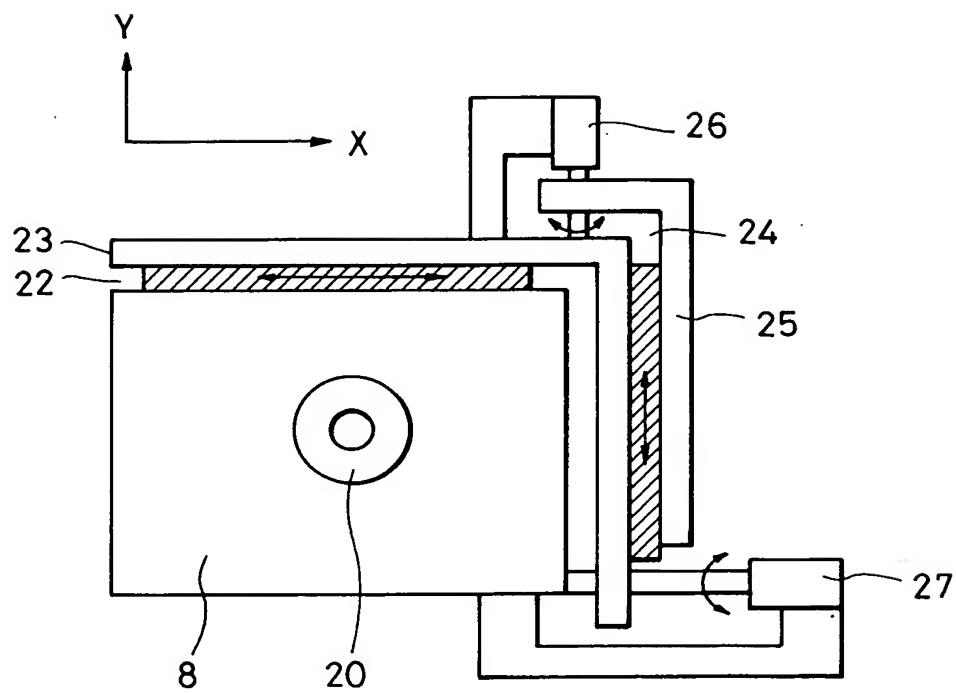


FIG. 6

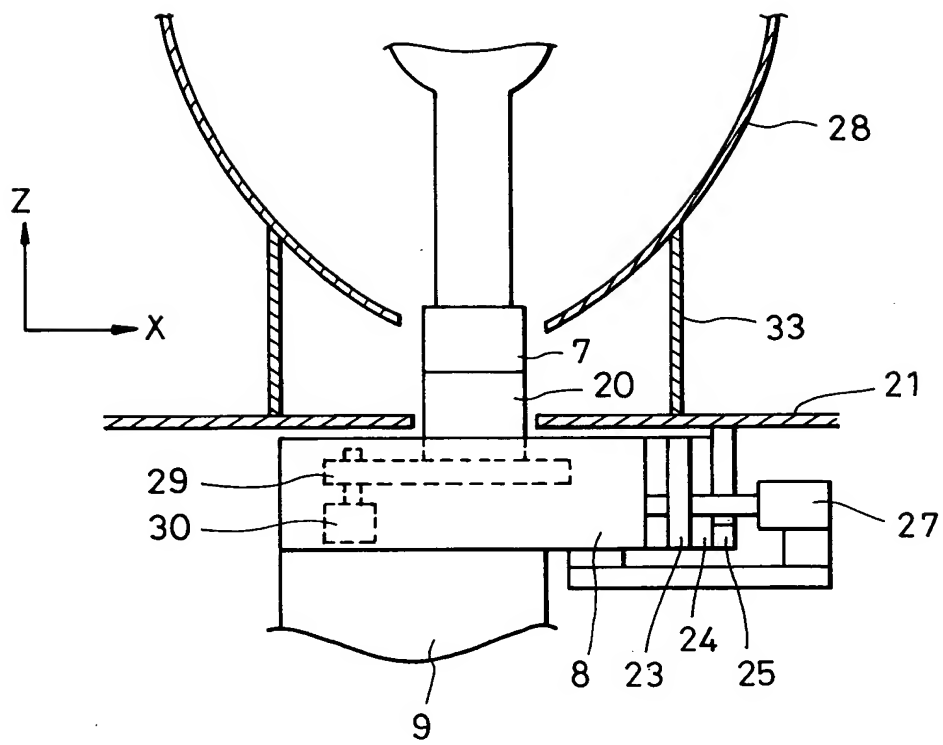


FIG. 7

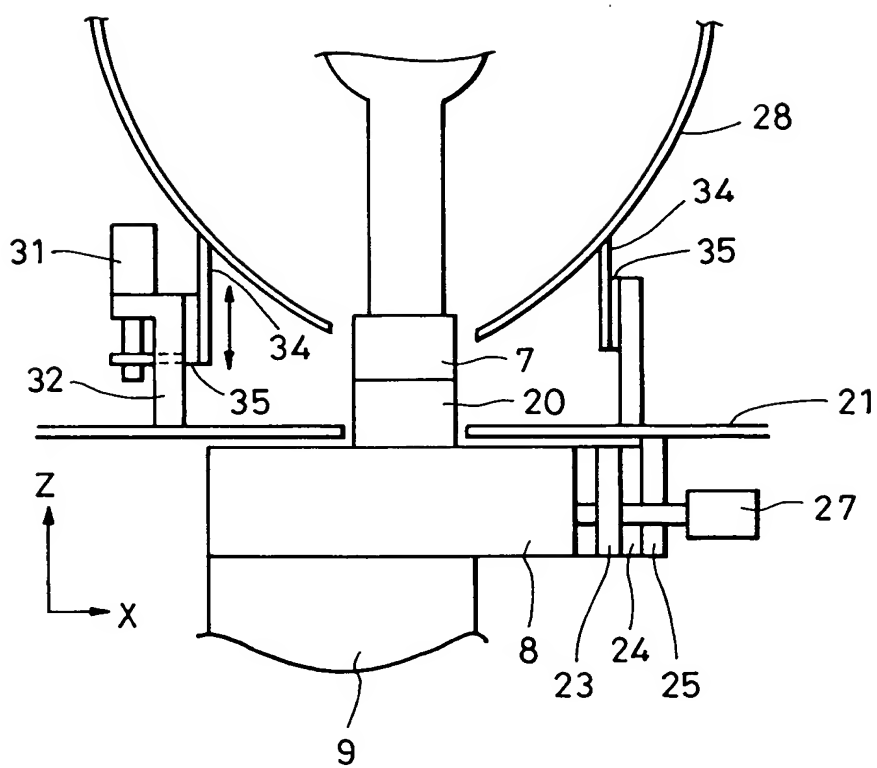
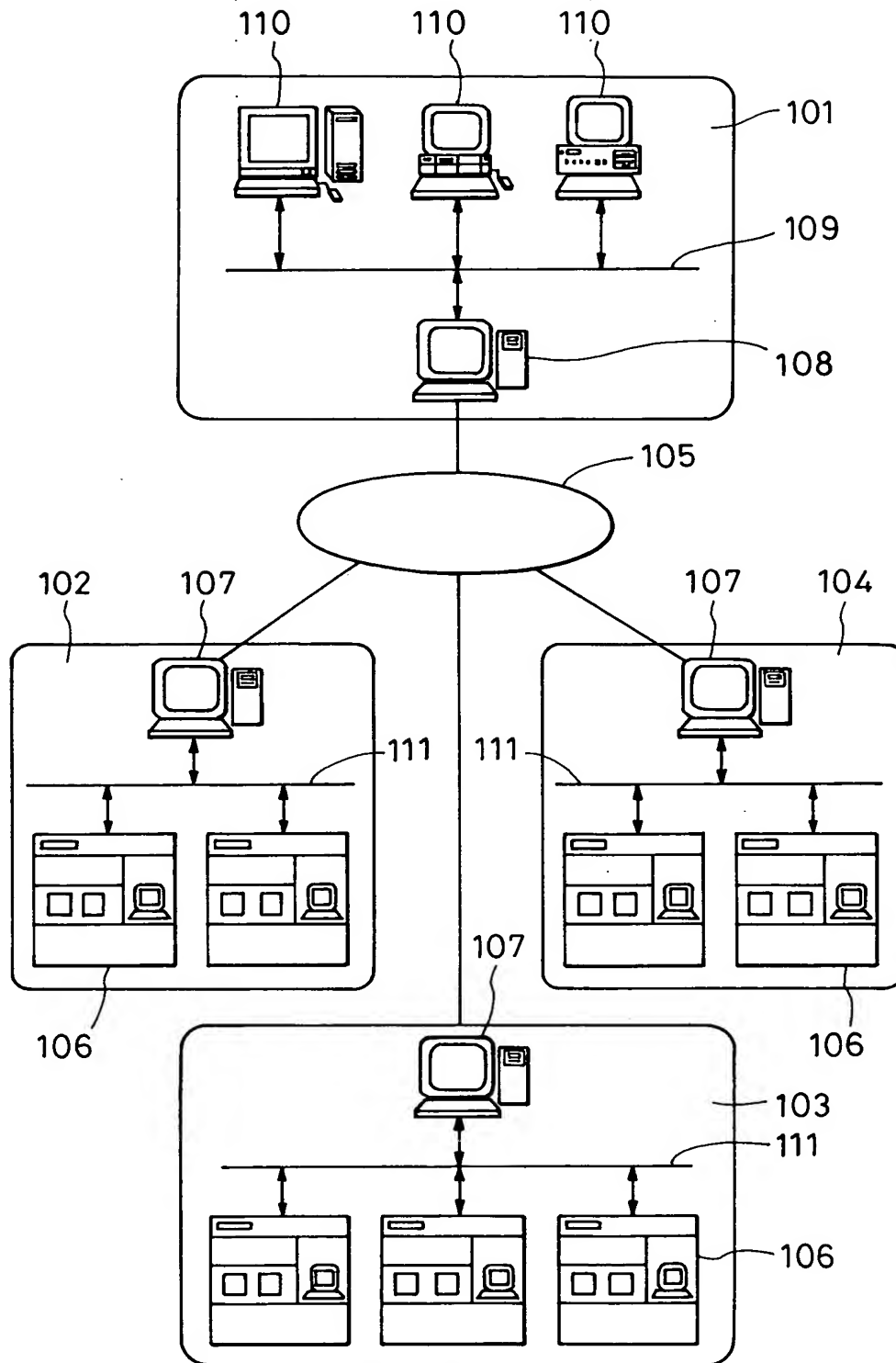
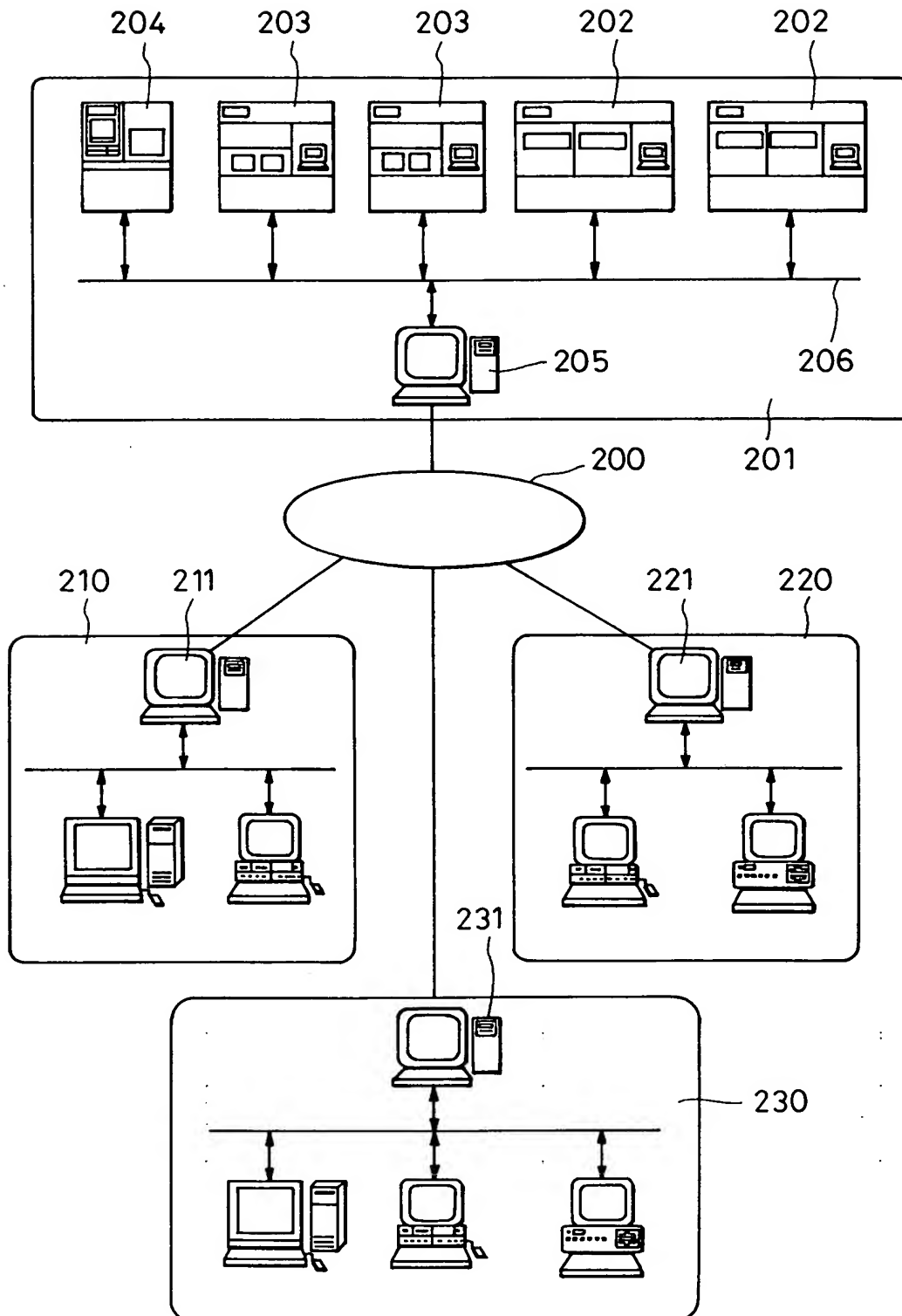


FIG. 8



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FIG. 9



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FIG. 10

URL

TROUBLE DATABASE INPUT SCREEN

DATA OF OCCURRENCE  404

MODEL  401

TITLE  403

EQUIPMENT SERIAL NO.  402

URGENCY  405

SYMPTOMS  406

MEASURES  407

RESULTS  408

410

[LINK TO DATABASE OF LIST OF RESULTS](#) 411

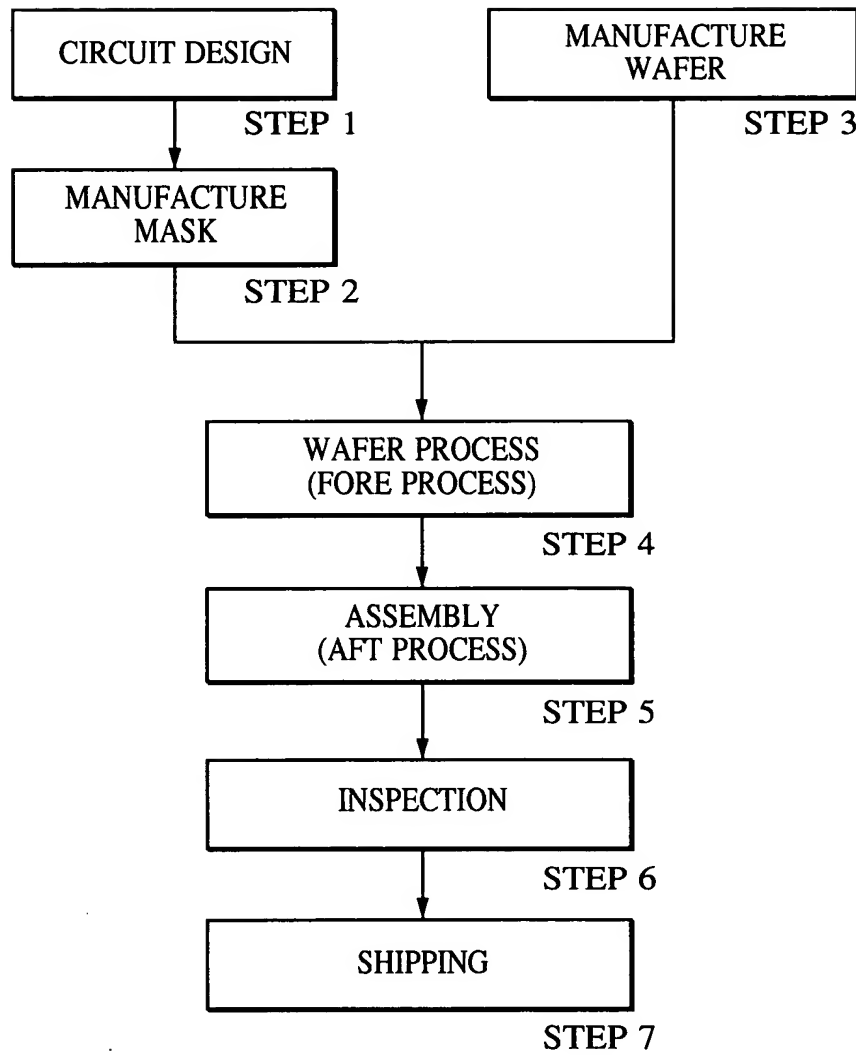
[SOFTWARE LIBRARY](#) 412

[OPERATING GUIDE](#)

2005.09.27 10:44:00

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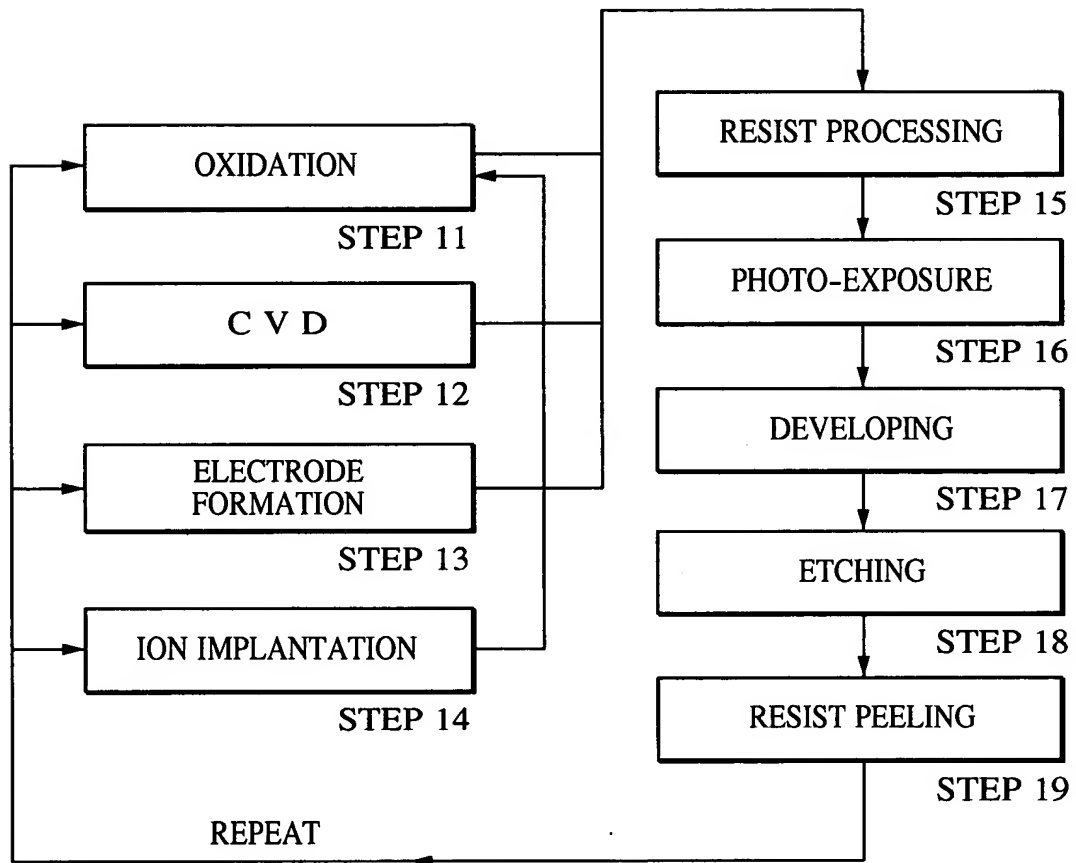
FIG. 11



FLOW FOR MANUFACTURING SEMICONDUCTOR DEVICES

205710" 2E574007

FIG. 12



WAFER PROCESS